



CyberOptics to Present Yield-Improving Measurement Methods for Semiconductor Fabs at Photomask Japan

Minneapolis, Minnesota — Mar. 31, 2017 — [CyberOptics® Corporation](#) (NASDAQ: CYBE), a leading global developer and manufacturer of high-precision 3D sensing technology solutions, will present two technical posters reviewing yield-improving measurement methods for Airborne Particles and Relative Humidity (RH) in semiconductor fabs at the [Photomask Japan](#) show, April 5-7 at the Pacifico in Yokohama, Japan. The session will take place on Thursday, April 6 from 16:20 – 17:50.

“There are several limitations with legacy Airborne Particle and Relative Humidity (RH) measurement methods. For example, hand-held sensors cannot easily access all areas, can be costly with downtime required to take the tool off-line and do not provide data in real-time,” said Mr. Yukinobu Hayashi, Senior Field Applications Engineer, CyberOptics. “By contrast, wireless, reticle-like measurement devices travel where a reticle travels and can collect and display data in real-time – speeding processes and saving expense.”

Whether for diagnostics, qualification or maintenance, semiconductor fab equipment or process engineers can efficiently and effectively take measurements and make adjustments using objective and reproducible real-time data from wireless reticle-like devices.

CyberOptics’ WaferSense® and ReticleSense® Line

The WaferSense measurement portfolio including the Auto Leveling System (ALS), the Auto Gapping System (AGS), the Auto Vibration System (AVS), the Auto Teaching System (ATS), the Airborne Particle Sensor (APS), the advanced Airborne Particle Sensor (APS2) and the new Auto Multi Sensor (AMS) are available in various wafer shaped form factors depending on the device, including 150mm, 200mm and 300mm wafer sizes. The ReticleSense measurement portfolio including the Airborne Particle Sensor (APSR & APSRQ) and next-generation APS2, the Auto Leveling System (ALSR) and the Auto Multi Sensor (AMSR) are available in a reticle shaped form factor.

About CyberOptics

CyberOptics Corporation (NASDAQ: CYBE) is a leading global developer and manufacturer of high precision sensing technology solutions. CyberOptics sensors are being used in general purpose metrology and 3D scanning, surface mount technology (SMT) and semiconductor markets to significantly improve yields and productivity. By leveraging its leading edge technologies, the company has strategically established itself as a global leader in high precision 3D sensors, allowing CyberOptics to further increase its penetration of its key vertical segments. Headquartered in Minneapolis, Minnesota, CyberOptics conducts worldwide operations through its facilities in North America, Asia and Europe.

Statements regarding the Company’s anticipated performance are forward-looking and therefore involve risks and uncertainties, including but not limited to: market conditions in the global SMT and semiconductor capital equipment industries; increasing price competition and price pressure on our product sales, particularly our SMT systems; the level of orders from our OEM customers; the availability of parts required to meet customer orders; unanticipated product development challenges; the effect of world events on our sales, the majority of which are from foreign customers; rapid changes in technology in the electronics markets; product introductions and pricing by our competitors; the success

of our 3D technology initiatives; the success of CyberGage360; and other factors set forth in the Company's filings with the Securities and Exchange Commission.

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